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Front Matter: Volume 11872

, "Front Matter: Volume 11872," Proc. SPIE 11872, Advances in Optical Thin Films VII, 1187201 (19 October 2021); doi: 10.1117/12.2614849

SPIE.

Event: SPIE Optical Systems Design, 2021, Online Only

PROCEEDINGS OF SPIE

Advances in Optical Thin Films VII

Michel Lequime

Detlev Ristau

Editors

13–17 September 2021

Online Only, Spain

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INEUSTAR/INDUCIENCIA (Spain)

Published by

SPIE

Volume 11872

Proceedings of SPIE 0277-786X, V. 11872

SPIE is an international society advancing an interdisciplinary approach to the science and application of light.

Advances in Optical Thin Films VII, edited by Michel Lequime, Detlev Ristau, Proc. of SPIE Vol. 11872
1187201 · © 2021 SPIE · CCC code: 0277-786X/21/\$21 · doi: 10.1117/12.2614849

Proc. of SPIE Vol. 11872 1187201-1

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Please use the following format to cite material from these proceedings:

Author(s), "Title of Paper," in *Advances in Optical Thin Films VII*, edited by Michel Lequime, Detlev Ristau, Proc. of SPIE 11872, Seven-digit Article CID Number (DD/MM/YYYY); (DOI URL).

ISSN: 0277-786X

ISSN: 1996-756X (electronic)

ISBN: 9781510645882

ISBN: 9781510645899 (electronic)

Published by

SPIE

P.O. Box 10, Bellingham, Washington 98227-0010 USA

Telephone +1 360 676 3290 (Pacific Time)

SPIE.org

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